

Metrology of High-Power Laser-Sustained Plasma Light Sources in DUV and VUV spectral regions

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KLA a leading company in metrology and inspection in semiconductor industry employs VUV (120-190 nm) and DUV (190-450 nm) spectral regions for inspection of wavers and reticles. In this presentation, we discuss challenges of conducting accurate calibrated measurements of spectral radiance and irradiance in this spectral range and techniques and apparatus we employ.